

PATENT



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In re Patent Application of

: Docket: YOR920000344US1

Jack O. Chu et al.

: Group Art Unit: 2813

Serial No.: 09/692,606

: Examiner: E. Kielin

Filed: October 19, 2000

: Date: October 26, 2001

For: Layer Transfer of Low Defect SiGe Using an Etch-back Process

**Information Disclosure Statement
under 37 CFR 1.97(b) (3)**

Commissioner for Patents
Washington, D.C. 20231

Sir:

Listed on form PTO-1449 are a number of documents which may be material to the examination of the above-referenced application. It is respectfully requested that the Examiner consider each of the cited documents and return an initialed copy of the form PTO-1449.

In accordance with 37 CFR 1.97(b), this information disclosure statement is being filed within three months of the filing date of the application or before the mailing date of the first Office Action on the merits, which ever event occurs last.

Respectfully submitted,
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